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INFORMATION DISCLOSURE STATEMENT

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Applicant: Naoaki YAMAGUCHI et al.

Filing Date: January 4, 2002

Group: 1746

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Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date (if appropriate)
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Examiner Anita Alambas

Date Considered 2/10/03

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FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation Yes No	
<i>XXXX</i>	05-243576	09/21/1993	Japan			Abstract	
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